



**SUPPLEMENTAL INFORMATION CITED BY APPLICANTS THAT MAY BE MATERIAL  
TO THE PROSECUTION OF THE SUBJECT APPLICATION**

Applicants: F.M. Schellenberg et al. Attorney Docket No.: MEGC122529  
Application No.: 10/811,418 Art Unit: 2825 / Confirmation No.: 2647  
Filed: March 26, 2004 Examiner: Binh C. Tat  
Title: CREATING PHOTOLITHOGRAPHIC MASKS

**U.S. PATENT DOCUMENTS**

*Examiner Cite Initials No.	Document No.	Kind Code	Date (mm/dd/yyyy)	Name
<u>BV</u> U16	6,416,907	B1	07/09/2002	Winder et al.
<u>BO</u> U17	6,620,561	B2	09/16/2003	Winder et al.

**FOREIGN PATENT DOCUMENTS**

*Examiner Cite Initial No.	Document No.	Kind Code	Publication Date (mm/dd/yyyy)	Country	English Abstract Translation Provided Provided
None					

**OTHER INFORMATION**

**(Including Author, Title, Date, Pertinent Pages, Etc.)**

*Examiner Cite Initial No.
None

**Examiner**

**Date Considered**

B. Tat

07/15/06

\*Examiner: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. § 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

RCT:jh

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